

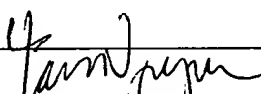
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				Filing Date			
				First Named Inventor			
				Group Art Unit			
Examiner Name				Attorney Docket Number			
Sheet 1 of 1				740819-595			
U.S. PATENT DOCUMENTS							
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FOREIGN PATENT DOCUMENTS							
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LN		Japan	07-153662	Toshihiko	06/16/1995		Abstract
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LN		R.R. Kunz et al., "Outgassing of organic vapors from 193 nm photoresists: Impact on atmospheric purity near the lens optics", J. Vac. Sci. Technol., B 17(6), pp. 3330-3334, Nov/Dec 1999.					
LN		H.C. Pfeiffer et al., "Projection exposure with variable axis immersion lenses: Next generation lithography", J. Vac. Sci. Technol., B 17(6), pp. 2840-2846, Nov/Dec 1999.					
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